



INFORMATION DISCLOSURE STATEMENT BY APPLICANT	Application Number	10/700,279
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	First Named Inventor	Jun Yan
	Group Art Unit	To be Assigned
	Examiner Name	To be assigned
Page 1 of 2	Attorney Docket Number	MVIS 02-24

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Examiner Initials	Document Number	Country	Date of Publication (MM-DD-YYY)	English Translation Provided?
WY	WO025170 A1	PCT	02/22/2003	G02B 26/08

IDC-Other Ref -2

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS	
Examiner Initials	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.
WY	CONANT, NEE, LAU and MULLER, "A Fast Flat Scanning Micromirror," 2000 Solid-State Sensor and Actuator Workshop, Hilton Head, SC, June 2000, pp.6-9
WY	CONANT, NEE, LAU and MULLER, "Dynamic Deformation of Scanning Micromirrors," presented at IEEE/LEOS Optical MEMS 2000, Kauai, Hawaii, August 2000

Examiner Signature		Date Considered	6/10/05
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